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Technology Center 2600

Washington, D.C. 20231

Fr: George O. Saile, Reg. No. 19,572 20 McIntosh Drive Poughkeepsie, N.Y. 12603

Subject:

Serial No. 09/993,067 11/14/01

Kuo-Chen Lin, Ming-Hong Hsieh

A METHOD AND APPARATUS FOR DISPLAYING PRODUCTION DATA FOR IMPROVED MANUFACTURING DECISION MAKING

Grp. Art Unit: 2672

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation In An Application.

The following Patents and/or Publications are submitted to comply with the duty of disclosure under CFR 1.97-1.99 and 37 CFR 1.56. Copies of each document is included herewith.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner of Patents and Trademarks, Washington, D.C. 20231, on January 9, 2002.

Stephen B. Ackerman, Reg.# 37761

Signature/Date

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- U.S. Patent 5,612,886 to Weng, "Method and System for Dynamic Dispatching in Semiconductor Manufacturing Plants," discloses a manufacturing control system using a computer control of workflow.
- U.S. Patent 5,818,716 to Chin et al., "Dynamic Lot Dispatching Required Turn Rate Factory Control System and Method of Operation Thereof," teaches a dispatching algorithm for use in integrated circuit manufacture.
- U.S. Patent 5,559,710 to Shahraray et al., "Apparatus for Control and Evaluation of Pending Jobs in a Factory," discloses a system and a method to schedule the release of production lots into a factory.
- U.S. Patent 5,889,673 to Pan et al., "Manufacturing Method and System for Dynamic Dispatching of Integrated Circuit Wafer Lots," teaches a system and a method to automatically and to dynamically dispatach lots in an IC manufacturing environment.
- U.S. Patent 5,841,677 to Yang et al., "Method and Apparatus for Dispatching Lots in a Factory," discloses a system and a method to automatically dispatch lots to available machine processes.

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U.S. Patent 5,768,133 to Chen et al., "WIP/MOVE

Management Tool for Semiconductor Manufacturing Plant and

Method of Operation Thereof," teaches a system and a method for interactive data processing in an IC manufacturing plant.

Sincerely

Stephen B. Ackerman,

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